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	Application No.	Applicant(s)		
•	10/521,009	LARSEN ET AL.		
Notice of Allowability	Examiner	Art Unit		
	Sang Nguyen	2886		
The MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT I of the Office or upon petition by the applicant. See 37 CFR 1.33	S (OR REMAINS) CLOSED 5) or other appropriate comm RIGHTS. This application is	in this application. If not included nunication will be mailed in due co	ourse. THIS	
1. \boxtimes This communication is responsive to <u>Preliminary Amenda</u>	ment on 01/12/05.	•		
2. X The allowed claim(s) is/are 1-23, 26-48, and 51-52 which	have renumbered as indica	<u>te 1-48</u> .		
 Acknowledgment is made of a claim for foreign priority of a) All b) Some* c) None of the: Certified copies of the priority documents have a copies of the priority documents have a copies of the certified copies of the priority o	ve been received. ve been received in Applicati ocuments have been receive " of this communication to fil	ion No ed in this national stage application		
4. A SUBSTITUTE OATH OR DECLARATION must be sub- INFORMAL PATENT APPLICATION (PTO-152) which gi	mitted. Note the attached EX ves reason(s) why the oath o	KAMINER'S AMENDMENT or NO or declaration is deficient.	TICE OF	
5. CORRECTED DRAWINGS (as "replacement sheets") mi	ust be submitted.			
(a) including changes required by the Notice of Draftspe		w (PTO-948) attached		
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date	·			
(b) including changes required by the attached Examine Paper No./Mail Date	r's Amendment / Comment o	or in the Office action of		
Identifying indicia such as the application number (see 37 CFR each sheet. Replacement sheet(s) should be labeled as such in	1.84(c)) should be written on the header according to 37 C	the drawings in the front (not the b	ack) of	
 DEPOSIT OF and/or INFORMATION about the dep attached Examiner's comment regarding REQUIREMENT 			te the	
Attachment(s) 1. ⊠ Notice of References Cited (PTO-892)	5. ☐ Notice of I	nformal Patent Application		
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)	_	6. ⊠ Interview Summary (PTO-413),		
3. ⊠ Information Disclosure Statements (PTO/SB/08),	Paper No	Paper No./Mail Date <u>09/12/07</u> . 7. ⊠ Examiner's Amendment/Comment		
Paper No./Mail Date <u>01/12/05</u> 4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. 🛭 Examiner's	s Statement of Reasons for Allow	ance	
	9. 🗌 Other	$ \lambda$		
		Sang H./Nguyen Primary Patent Exam Art Unit 2886	iner	

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EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Attorney Stephen Maebius (Reg. No. 35,264) on September 12, 2007.

The application has been amended as follows:

Claims 24-25 and 49-50 have been canceled.

The following is an examiner's statement of reasons for allowance:

Claims 1-23, 26-48, and 51-52 are allowed.

As to independent claims 1, 14, 26, and 39 are allowable over the prior art for at least the reason that the prior art of record, taken alone or in combination, fails discloses or render obvious a non-destructive method and apparatus for measuring geometrical profiles of periodic microstructures of a sample comprising all the specific elements with the specific combination including of resolving means for resolving the collected light into diffraction data relating to illumination angles, polarization angles, diffraction orders, and illumination wavelengths, and a reconstruction algorithm for determining the geometrical profile of the illuminated microstructures, the reconstruction algorithm being adapted to perform the following steps: comparing the resolved diffraction data with modeled diffraction data from a known geometrical profile, the

comparison taking both the 0'th and higher diffraction orders into account, the known geometrical profile being selected from a database of pre-defined families of profiles, the selection being performed using minimum norm techniques, repeating adjusting the geometrical profile of the known selected geometrical profile until the modeled diffraction data matches the resolve diffraction data within predetermined tolerances in combination with the rest of the limitation of claims, 14, 26, and 39.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sang Nguyen whose telephone number is (571) 272-2425. The examiner can normally be reached on 9:30 am to 7:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Tarifu Chowdhury can be reached on (571) 272-2800 ext. 86. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR.

Status information for unpublished applications is available through Private PAIR only.

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September 12, 2007

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